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Glass Carriers with Matched CTEs for Wafer Thinning Applications

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Glass Technology Leader

Corning Precision Glass Solutions

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Founded:

1851

Headquarters:

Corning, New York

Employees:

~ 49,500 worldwide

2020 Core Sales:

\$11.3 billion

Fortune 500 Ranking (2020):

279

Corning Incorporated is one of the world's leading innovators in materials science. For more than 165 years, Corning has applied its unparalleled expertise in glass science, ceramics, and optical physics to develop products and processes that have transformed industries and enhanced people's lives.

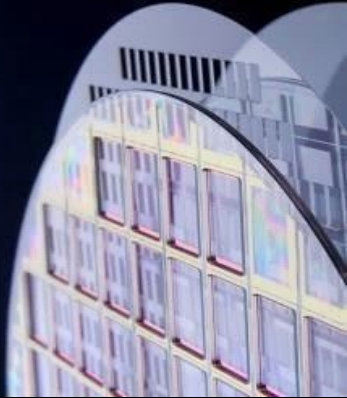
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Precision Glass
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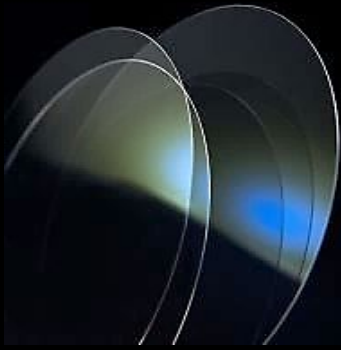
Corning Precision Glass Solutions offers industry leading wafer and panel format glass-based solutions.

Our products help customers deliver increasingly demanding functionality and form factor requirements in consumer devices and Internet of Things (IoT) applications.

*Wafer-Level Capping
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*Wafer-Level Optic
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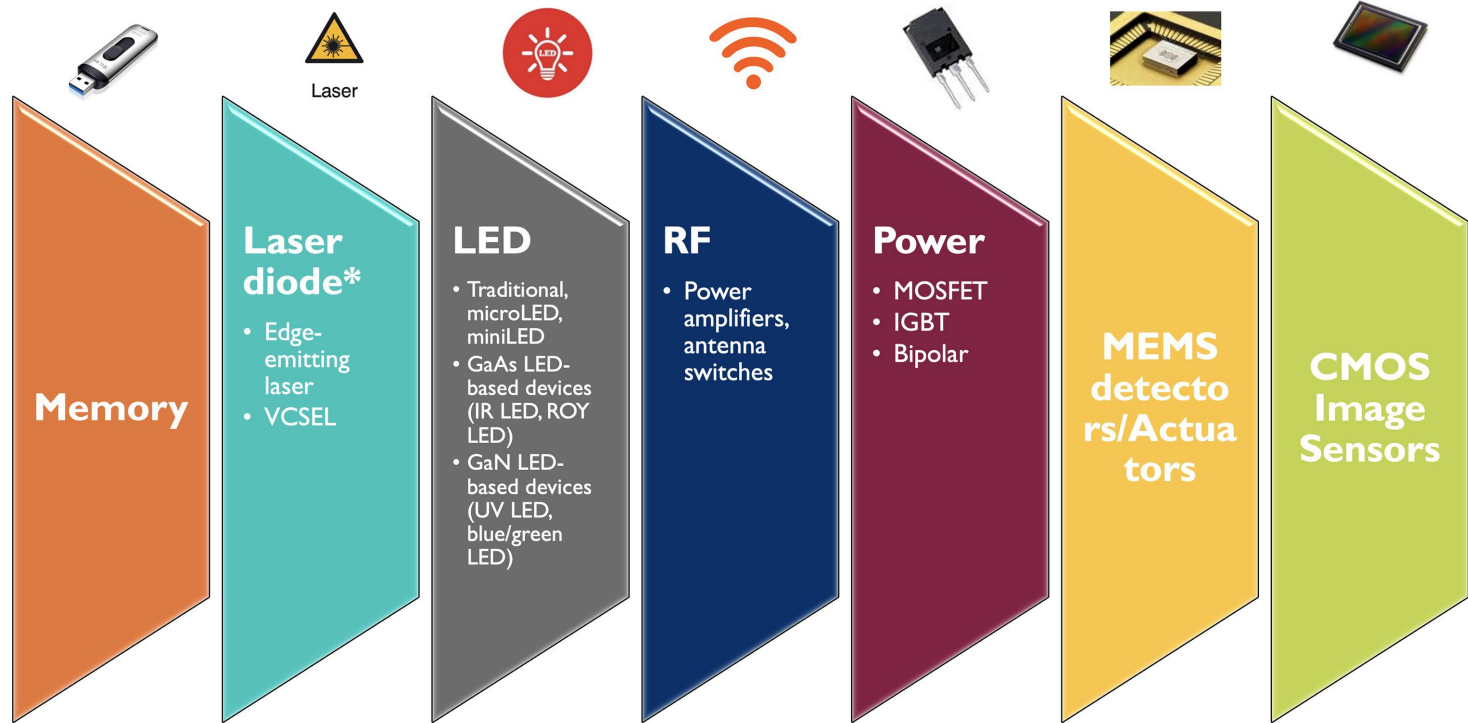
Carrier Solutions



*Custom Glass
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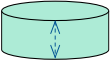
There are a Variety of Applications that Require Wafer Thinning Processes



Source: Yole Development

Semiconductor Wafer size and Thickness Trends are Driving Emerging Applications

Semiconductor wafer availability and trend

Wafer Diameter		100mm 4"	150mm 6"	200mm 8"	300mm 12"
Wafer thickness 	Silicon 	525 μ m	675 μ m	725 μ m	775 μ m
	SiC 		350 μ m 		
	GaAs 	625 μ m $\pm$ 25 μ m	675 μ m $\pm$ 25 μ m 		
	Sapphire 		675 μ m $\pm$ 25 μ m 		

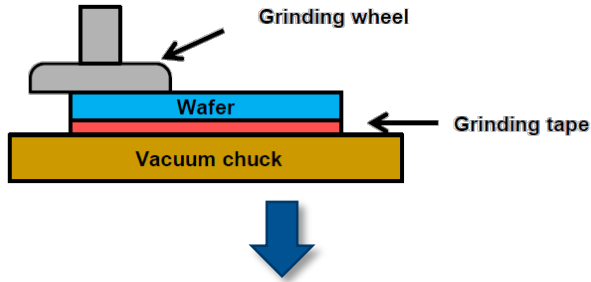
Industry trends for wafer thinning based on application

TODAY (2019)		TOMORROW (2025)	
MEMS substrates	370–250 μ	MEMS substrate	100 μ
MEMS capping	100–300 μ	MEMS capping	50 μ
ASIC MEMS	100–150 μ	ASIC MEMS	100 μ
CIS Packaging	140–200 μ	CIS Packaging	100 μ
CIS BSI	<10 μ (3–5 μ)	CIS BSI	< 10 μ
Memory	50 μ m	Memory	20 μ
Logic	50 μ	Logic	30 μ
Power Devices	60–110 μ (depending on the voltage applied)	Power Devices	<60 μ
RF Devices	130 μ	RF Devices	>200 μ
LEDs	100 μ	LEDs	80 μ
Laser diode	100 μ	Laser diode	

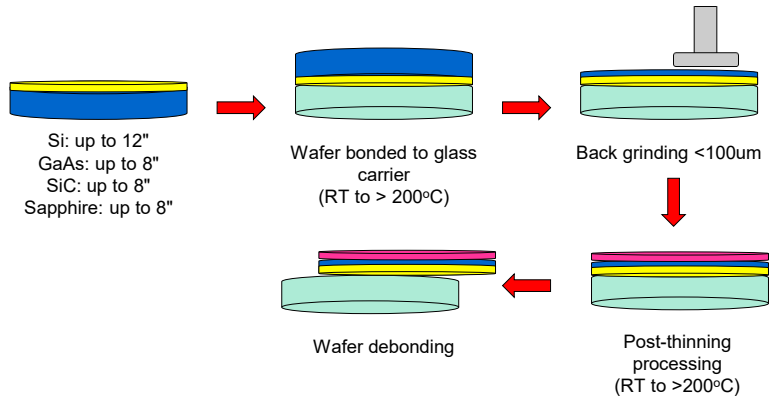
Transition wire-bond $\rightarrow$ flip-chip technology

Source: Yole Development

Wafer Thinning Process and Challenges



Typical Wafer Thinning and Processing Flow



Wafer Thinning Challenges

- Grinding damage
- Wafer breakage
- Edge chipping
- Wafer warpage → Post thinning processes
- General handling



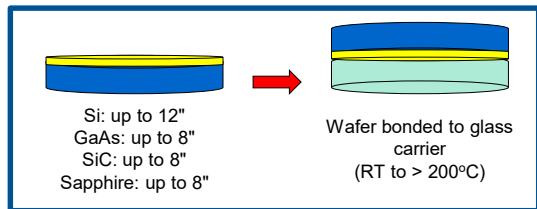
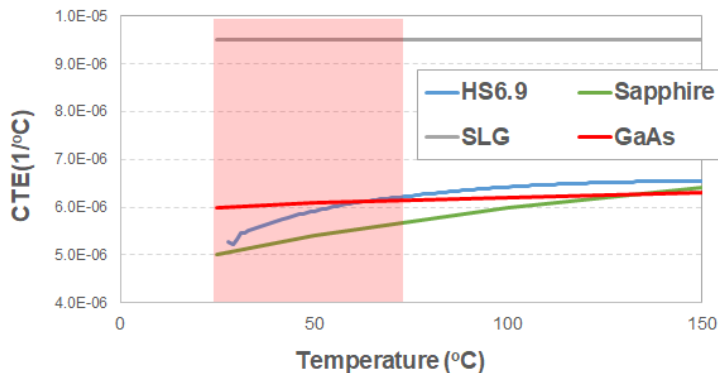
When wafers are thinned to <100 um or require post-thinning processing, **glass carrier** is a preferred choice

Wafer Warp During Bonding Process

Δ CTE of glass substrate, device wafer and adhesive: modeling & experimental data

Minimizing Δ CTE between carrier substrate and wafer at processing temperature is important

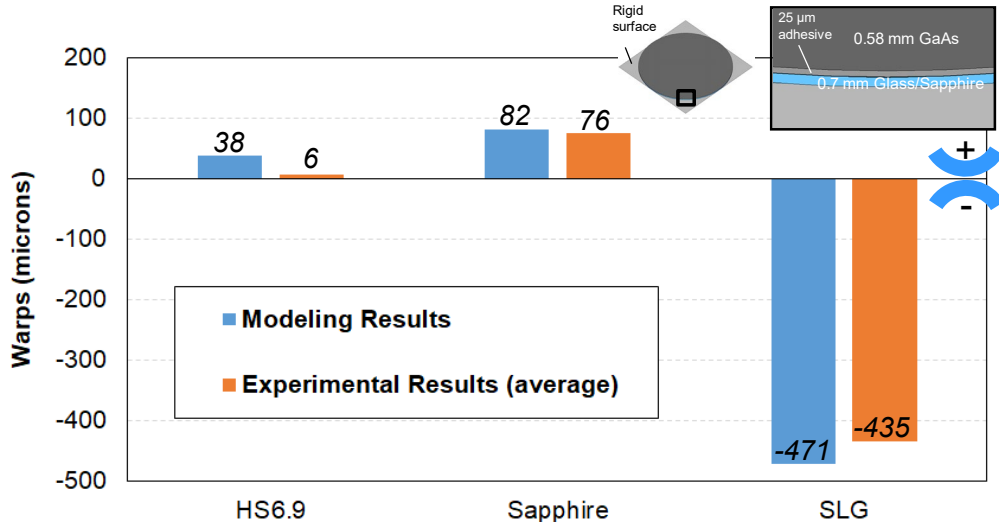
*Glass CTE is not a constant value.
It changes as a function of temperature.*



In-process warp of bonded GaAs wafers: Modeling and experimental data

Modelling assumption:

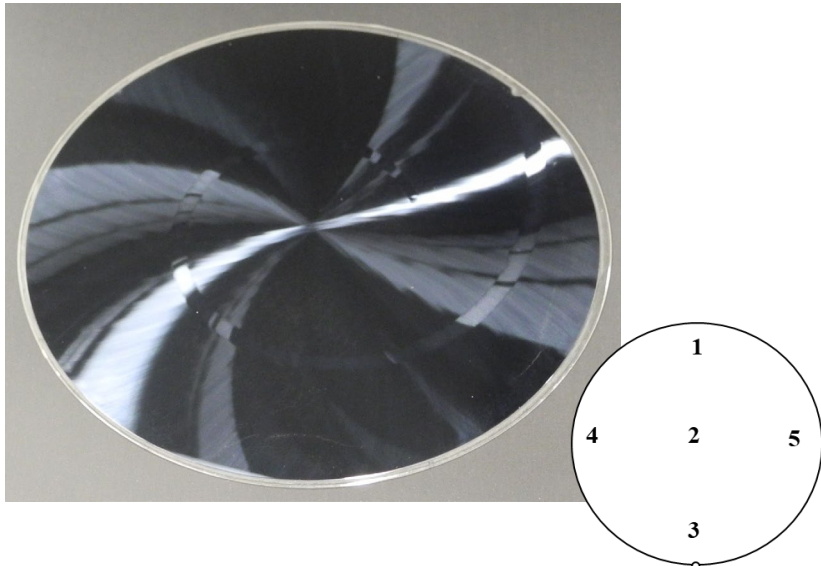
- high temperature GaAs wafer bonding with different substrate
- Substrate thickness 0.7mm and adhesive thickness 25um
- Initial GaAs wafer thickness 580um
- Wafer diameter 150mm (6")
- Stress-free temp: 70°C (adhesive Tg)



Bonded Wafer after Back Grinding

HS6.9 successfully support wafer thinning: experimental result

Bonded GaAs on HS6.9 after back grinding



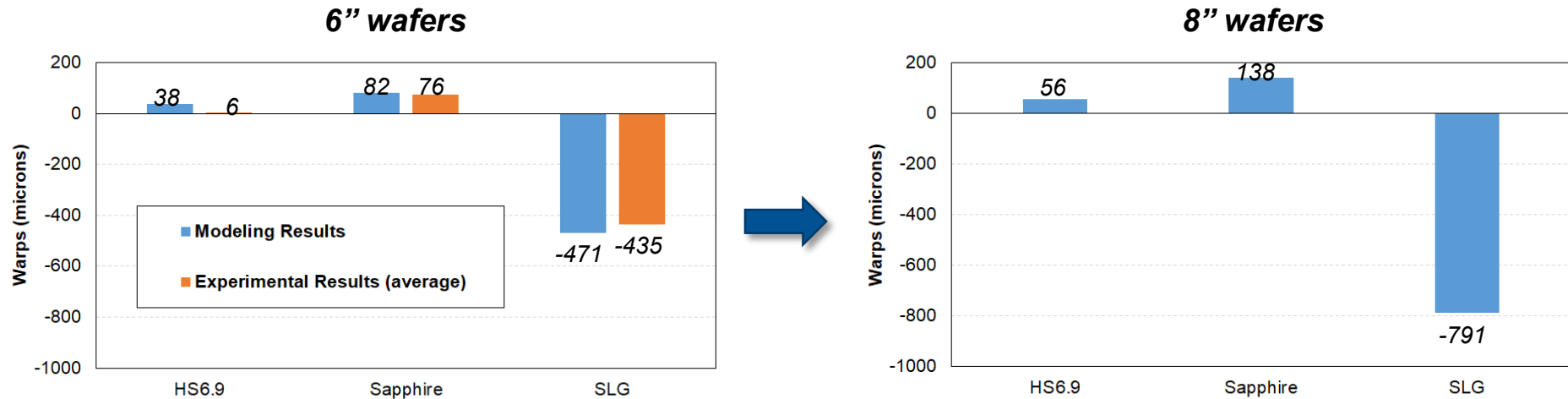
- Corning HS6.9 showed no process damage during thinning process
- Bonded GaAs wafer was ground to $\sim 125\mu\text{m}$ using Disco DAG810 automatic surface grinder

Carrier		Org. thickness	Final Thickness (μm) (Measurement points)						
Material	Thickness (μm)		1	2	3	4	5	Ave	TTV
HS6.9	700	1383	824.8	825.3	824.9	824.7	825.0	824.9	0.6

Wafer Warp During Bonding Process

In-process warp becomes bigger issue as device size increases from 6" to 8"

In-process warp of bonded GaAs wafers: Effect of substrate diameter



Modelling assumption:

- high temperature GaAs wafer bonding with different substrate
- Substrate thickness 0.7mm and adhesive thickness 25um
- Initial GaAs wafer thickness 580µm
- Wafer diameters 6" (150mm) and 8" (200mm)
- Stress-free temp: 70°C (adhesive Tg)

Glass Substrate is the Material of Choice

Device Packaging Conference 2021 - April 12-15, 2021

Inherent properties of glass mitigates industry challenges in wafer thinning

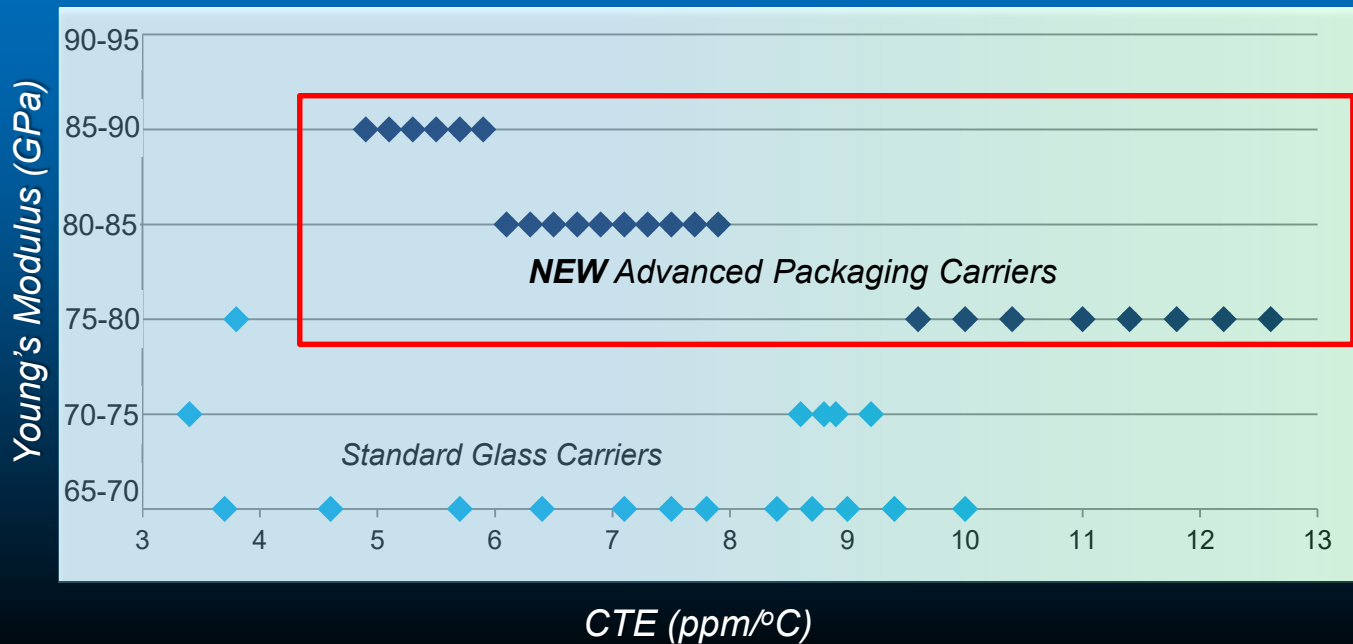
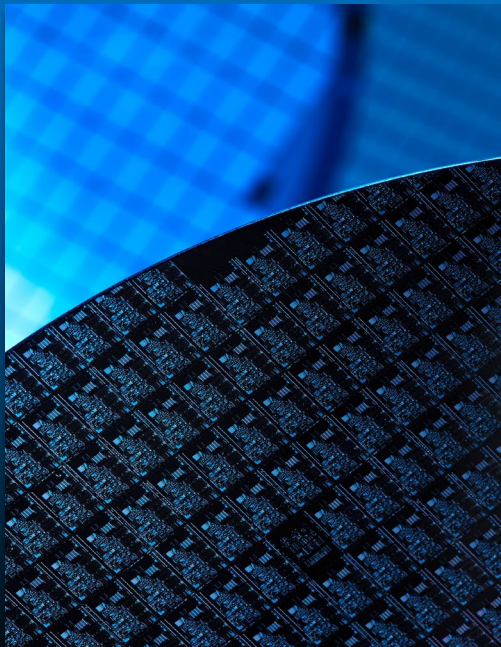
		Benefits of Wafer Thinning
Properties of Glass	Range of CTEs in fine granularity	$\downarrow \Delta \text{CTE} \rightarrow \downarrow \text{warp}$
	Optical transparency	Enables light based bonding/debonding
	Flatness & smoothness	Enables thinner device wafer $\ll 50 \mu\text{m}$
	High stiffness	$\downarrow \text{warp}$
	Size of glass substrates	$\downarrow \text{cost} + \downarrow \text{handling damage}$
	Variety of thicknesses	$\downarrow \text{warp} + \downarrow \text{handling damage}$
	Manufacturing scalability	Enables R&D + $\downarrow \text{cost}$

Corning Carrier Solutions

Device Packaging Conference 2021 - April 12-15, 2021

Ideally suited for wafer thinning applications

Corning has tailored its glass carriers by Young's Modulus, CTE, and freedom of wafer thickness to enable wafer thinning industry challenges



Corning Advanced Packaging Carriers (APC)

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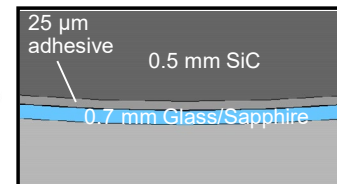
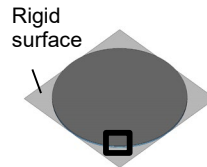
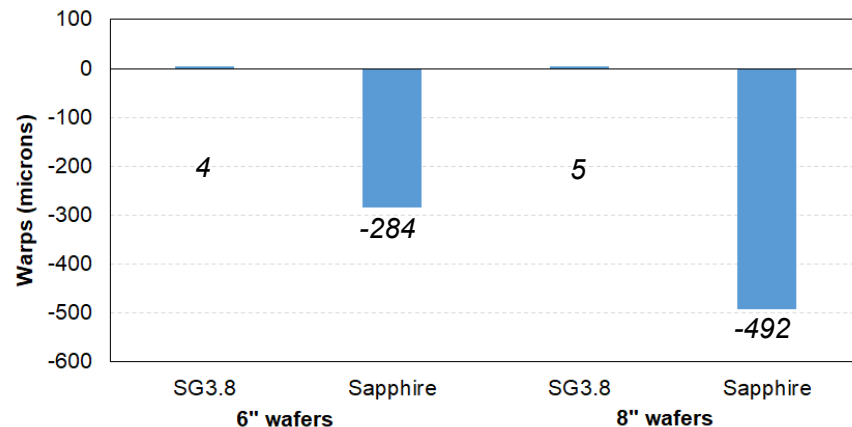
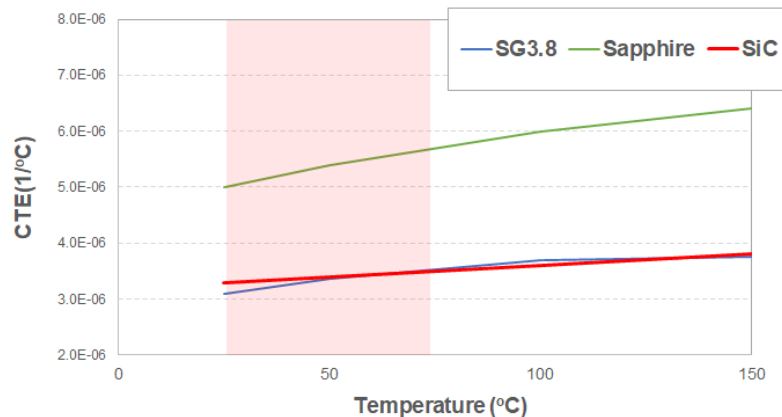
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1. Fine granularity of CTE's-minimize Δ CTE
2. High Stiffness: Increased YM & optimized thickness
3. 4-6 week lead time for samples and have sampled multiple customers to date

Wafer Bow During Thinning and Post Processing

Device Packaging Conference 2021 - April 12-15, 2021

Corning APC can address a very wide range of market needs



Modelled warps of bonded SiC wafers at 6" and 8" diameter; Stress-free temp: 70 $^\circ\text{C}$ (adhesive Tg)

Summary

- Wafer thinning is the industry trend due to 1) miniaturization, 2) better thermal management and 3) higher device performance
- CTE matching between device wafer and carrier at the processing temperature is imperative to minimize warp
- Glass can support CTE matching for any known wafer material
- Glass is the material of choice for growing device wafer form factor
- Corning is ready to support wafer thinning industry from R&D to high volume manufacturing

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Thank You

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